

Form PTO-1449

U.S. DEPARTMENT OF COMMERCE  
PATENT AND TRADEMARK OFFICEATTY. DOCKET NO.  
MI22-1114

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## U.S. PATENT DOCUMENTS

*Examiner Initial		Document Number	Date	Name	Class	Subclass	Filing Date If Appropriate
TSP	AA	4,568,565	02/1986	GUPTA ET AL.	427	53.1	8/14/84
TSP	AB	4,971,655	11/1990	STEFANO ET AL.	156	659.1	12/26/89
TSP	AC	5,240,739	08/1993	DOAN ET AL.	427	126.1	8/7/92
TSP	AD	5,376,405	12/1994	DOAN ET AL.	427	126.1	4/5/93
	AE						
	AF						
	AG						
	AH						
	AI						
	AJ						
	AK						

## FOREIGN PATENT DOCUMENTS

		Document Number	Date	Country	Class	Subclass	Translation	
							Yes	No
	AL							
	AM							
	AN							
	AO							
	AP							

## OTHER REFERENCES (including Author, Title, Date, Pertinent Pages, Etc.)

TSP	AR		ILDEREM, V., et al., "Optimized Deposition Parameters for Low Pressure Chemical Vapor Deposited
			Titanium Silicide", <i>Massachusetts Institute of Technology</i> , Vol. 135, No. 10, pp. 2590-96 (2/1988)
TSP	AS		NAGABUSHNAM, R.V., et al., "Kinetics and Mechanism Of The C49 to C54 Titanium Disilicide Phase Transformation
			Formation In Nitrogen Ambient", 5 pages (Published 11/1995)
	AT		

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U.S. DEPARTMENT OF COMMERCE  
PATENT AND TRADEMARK OFFICEATTY. DOCKET NO.  
MI22-1114SERIAL NO.  
09/233,377

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APPLICANT  
Micron Technology, Inc.FILING DATE  
January 18, 1999

GROUP

## U.S. PATENT DOCUMENTS

*Examiner Initial		Document Number	Date	Name	Class	Subclass	Filing Date If Appropriate
TSP	AA	5,997,634	12/7/99	Sandhu et al.	117	3	10/14/96
	AB						
	AC						
	AD						
	AE						
	AF						
	AG						
	AH						
	AI						
	AJ						
	AK						

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	AN							
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	AP							

## OTHER REFERENCES (including Author, Title, Date, Pertinent Pages, Etc.)

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